

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Keum Joo LEE, et al.

Art Unit: 1746

Serial No. 09/955,126

Examiner: Michael Kornakov

Filed: September 19, 2001

Confirmation No. 8415

For: METHOD OF CLEANING
DAMAGED LAYERS AND
POLYMER RESIDUE FROM
SEMICONDUCTOR DEVICE

Atty. Docket No. 259/011

AMENDMENT UNDER 37 C.F.R. § 1.111
(supplemental)

Commissioner for Patents
United States Patent and Trademark Office
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

INTRODUCTORY COMMENTS

Further to a telephone interview with the Examiner conducted on May 25, 2004, the following amendments and remarks are respectfully submitted in connection with the above-identified application:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in a listing of claims, which begins on page 3 of this paper.

Remarks begin on page 10 of this paper.